

Receipt date: 04/02/2010

Doc code: IDS

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10791334 - GAI: 1715

PFO/05/08a (01-10)

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	Filing Date		2004-03-01
	First Named Inventor	Gi Youl Kim	
	Art Unit	1792	
	Examiner Name	David P. Turocy	
	Attorney Docket Number	40004551-0025-002	

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	4	5879459		1999-03-09	Gadgil, Prasad N. et al.	
	5	6042652		2000-03-28	Hyun, Kwang-soo et al.	
	6	6174377		2001-01-16	Doering, Kenneth et al.	
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